

Title (en)
MICROFLUIDIC DEVICE AND MANUFACTURING METHOD THEREFOR

Title (de)
MIKROFLUIDISCHE VORRICHTUNG UND HERSTELLUNGSVERFAHREN DAFÜR

Title (fr)
DISPOSITIF MICROFLUIDIQUE ET SON PROCÉDÉ DE FABRICATION

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Abstract (en)
The present invention relates to a microfluidic device and a manufacturing method therefore and, more particularly, to a microfluidic device comprising: a first substrate layer; a second substrate layer formed on at least one surface of the first substrate layer; and a plurality of transducers formed on the surface of the first substrate layer and embedded in the second substrate layer, wherein the transducer comprises a conductive microfluidic channel. The present invention can provide an elastic wave substrate microfluidic device capable of controlling an elastic wave according to a property of a microparticle and capable of being manufactured without expensive equipment and complicated process procedures.

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